EMPLOYMENT OPPORTUNITIES

Post Doc Positions: High resolution *in situ* microscopy. Corrosion, advanced battery, electrochemistry, polymer, materials science, biology-SPM. Several locations: U.S., Japan, Europe. http://www.molec.com/jobs/postdoc.html

Electron Microscopist Position: Immediate opening for person with advanced degree or equivalent experience in TEM/SEM biological/virus work.. Three or more years experience in industrial experience preferred. Must be able to interpret cell and virus ultrastructure and viral morphogenesis. Person will be responsible to expand EM Department personnel and equipment, work with the R&D and quality control staff, and contribute to R&D staff publications. Salary and benefits commensurate with abilities and experience. Contact Dr. James Whitman, Phone: (301)470-3220 or Fax (301)497-9773

USED EQUIPMENT FOR SALE

NIKON LABOPHOT 2 Microscope: $1,850, **OLYMPUS BX-40 UIS:** $3,295, **OLYMPUS PM-10 CBAD Exposure Unit:** $1,295, **POLAROID 4x5 Back** with adaptor and cone mount: $750, **NIKON F3HP camera:** $625, **CONTAX-167MT Auto SLR:** $349. MICROGENICS: (707)277-7909

ISI-40 SEM with Kevex Unispec 7000 analytical spectrometer, best offer: (909)862-8494

Philips EM-400T-FEG (field emission gun) **TEM** complete with EDAX ECON detector, EDAX PV 9800 analyzer, STEM (PW6585) unit and air cooled water chiller. Also available: **Edax detector** (with Be window) and **Edax 9900 analyzer.** All items are in good working condition. For details call: (203)389-6065 or FAX (203)387-3574.

Sorvall/Dupont MT6000 and MT2B Ultramicrotomes, GKM Glass Knife Maker, JB4 Microtome. Complete with accessories and warranty, reconditioned by factory trained rep. For prices, call Bill McGee, Microtome Service Company: (315)451-1404

LKB8800 ULTRATOME III with power suppy and accessories, **B7800 Knifemaker, Philips EM301 SEM** with standard high resolution and many extras: (408)478-7252 or (409)737-5070.

MILITARY RESEARCH LAB IS CLOSING - Military contractor is selling at drastically reduced prices its Reichart Polycut S motorized sliding microtome, refrigerated and rotary microtomes, Sorvall ultramicrotome, Gatan Model 600 dual ion mill. Fisher embedding center, stereo microscopes, Perkin Elmer microdensitometer and LECO sulfur analyzer. For specification sheets, call: (202)544-0836.

Upgrade Now!

VERSION 2.0

Desktop Microscopist

Diffraction Simulation & Analysis Software
for the Macintosh®

2 Beam Dynamical Dislocation & Stacking Fault Simulation

Full SAD Simulations with Spots, K-lines and Streaking

Lattice Calculation from Patterns

(just a few of the) NEW FEATURES!

Full Dynamic CBED Simulation

Rapid Search of EDD, PDF, and NBS/NIST Crystal Databases (purchased separately)

Comparison of Diffractomer Spectra

http://www.Rt66.com/~virtlabs/

VIRTUAL LABORATORIES

tel: 1-505-828-1640 • fax: 1-505-822-9759

NEW PRODUCT NEWS

FEI Company Introduces the DualBeam XL830 FIB/SEM Workstation for Advanced 3D Defect Review, Analysis and Characterization

FEI Company introduces the all-new DualBeam XL830™ FIB/SEM Workstation, the newest member of FEI's XL800 family of advanced, 3-dimensional defect review, analysis, and characterization tools. The system's new SEM column provides significant breakthroughs relating to resolution and low voltage operation, with 3 nm resolution from 1 to 30 kV. The all-new electron column offers balanced-field, in-lens detection to provide exceptional topographic detail, down hole visibility, and enhanced grain boundary imaging. In the XL830 system, rapid FIB milling for cross-sectioning and imaging with the SEM at very high resolution are completely simultaneous operations. The Predictive User Interface™ provides "true ease of use" by keeping the submicron defect in the field of view during various operations and viewing from various angles.

FEI Company, 7451 N.W. Evergreen Parkway, Hillsboro, OR 97124, Tel.: (503)640-7500, Fax: (503)640-7509

New Hitachi SEMS Feature Windows 95 Control

The new S-4700 FE SEM and S-3500N Variable Pressure SEM match Hitachi's traditional high-performance, high-resolution microscopy with the convenience of PC-controlled electronics in the comfortable GUI environment of the Windows™ 95 operating system.

Offering as standard the easy mouse-based operation familiar to computer users, the SEMs can be supplied with conventional control panels for use by those choosing non-computer-type control.

Both SEMs incorporate high-density frame memories with maximum pixel counts of 2,560 x 1,920 for quality image recording and storage. The instruments also include *Rapid Image Shift Movement (RISM)* capability for fast, accurate navigation about the specimen, and are available with a *Hi Mouse* feature that allows easy EDX operation from the SEMs.

The S-4700's new objective lens contributes to superior resolution (25 Å at 1 kV) which is maintained at longer working distances as well as at high tilt angles on large samples. And, in its analytical mode, the instrument permits EDX operation concurrent with high-resolution microscopy.

The S-3500N can be counted on for high-resolution imaging whether operated in its conventional high-vacuum or its variable pressure mode. The latter mode allows microscopy of wet, oily and non-conductive samples in their natural state without the need for conventional sample preparation.

Nissei Sangyo America, Ltd., 755 Ravendale Drive, Mountain View, CA, tel.: (800)227-8877, eMail: sidsales@nissei.com

New Windows™ Software Extends Capabilities of Philips CM Series Transmission Electron Microscopes

Philips Electron Optics introduces four new software packages for its CM series of TEMs. The software operates in the Windows™ environment and includes packages for asbestos analysis, grid scanning, XY control and photomontage.

- The all-new Windows CM Asbestos Analysis package provides an easy to use method for detecting asbestos reliably and accurately.
- Windows CM Grid Scanning greatly simplifies systematic searches.
- Windows CM XY Control controls specimen stage movement.
- Windows CM Photomontage provides automatic determination and recording of photomontage exposures, in case it is impossible to cover the entire area of interest in a single micrograph.

Philips Electron Optics, 85 McKee Drive, Mahwah NJ 07430, Tel.: (201)529-3800, Fax: (201)529-2252

Circle Reader Inquiry #23

CrossMark
https://doi.org/10.1017/S1551929500070279 Published online by Cambridge University Press